

32. (New) The apparatus according to claim 29, wherein the detector structure is applied on a back side of the substrate of the optical imaging system.

33. (New) The apparatus according to claim 19, further comprising:

a membrane supporting the detector structure.

34. (New) The apparatus according to claim 19, wherein the detector structure includes thermocouples.

35. (New) The apparatus according to claim 19, wherein the optical imaging system and the detector structure are formed by joining two wafers prior to sectioning.

36. (New) A method for producing an apparatus for sensing electromagnetic radiation, comprising:

producing an optical imaging system and a detector structure in monolithic micromechanical fashion, the detector structure for sensing the electromagnetic radiation, the optical imaging system for forming an image of a subject to be imaged onto a plane of the detector structure.

REMARKS

This Preliminary Amendment cancels, without prejudice, claims 1-18 in the underlying PCT application PCT/DE99/01869. This Preliminary Amendment further cancels, without prejudice, revised claim 1 in the annex to the International Preliminary Examination Report, and adds new claims 19-36. The new claims, inter alia, conform the claims to U.S. Patent and Trademark Office rules and do not add new matter to the application.

The above amendments to the title, the specification and the abstract conform the title, the

specification and the abstract to U.S. Patent and Trademark Office rules, and do not introduce new matter into the application.

The underlying PCT application PCT/DE99/01869 includes an International Search Report, dated January 13, 2000. An English translation of the Search Report is provided herewith.

The underlying PCT application also includes an International Preliminary Examination Report ("IPER"), dated September 19, 2000. An English translation of the IPER is included herewith.

It is respectfully submitted that the subject matter of the present application is new, non-obvious, and useful. Prompt consideration and allowance of the application are respectfully requested.

Respectfully submitted,

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